

ABSTRACT

SUBSTRATE TRANSPORT APPARATUS AND METHOD

An object of the invention is to provide a substrate transport apparatus which enables prompt transfer of a substrate, and a substrate processing apparatus incorporating this. A substrate transport apparatus of the invention comprises a transport arm (45, 46, 145, 146) for supporting a peripheral portion of a substrate (W) at at least two places on the peripheral portion, and transporting the substrate to a stage (7). The transport arm comprises: a first arm (45) having a first support portion (45e) for supporting a rear face of one side of the peripheral portions of the substrate in a transport direction (C-D) of the substrate, and a first facing portion (45f) provided on the first support portion and facing a side face of the one peripheral portion of the substrate; a second arm (46) having a second support portion (46e) for supporting a rear face of the other side of the peripheral portions of the substrate in said transport direction of the substrate, and a second facing portion (46f) provided on the second support portion, and facing a side face of the other peripheral portion of the substrate; and a drive mechanism (43, 43a, 45a, 46a) for driving each of the first arm and the second arm so as to approach and separate from each other.